

US Dept. of Commerce PATENT & TRADEMARK OFFICE			ATTY DOCKET NO. 128375	APPLICATION NO. 10/582,268
INFORMATION DISCLOSURE STATEMENT (Use several sheets if necessary)			APPLICANT(S) Yasufumi NISHII et al.	
			FILING DATE June 9, 2006	
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AP3 Rec'd PCT/PTO 19 JUN 2009

Sheet 1 of 1

Form PTO-1449 (REV. 1/06) US Dept. of Commerce PATENT & TRADEMARK OFFICE INFORMATION DISCLOSURE STATEMENT (Use several sheets if necessary)			ATTY DOCKET NO. 128375	APPLICATION NO. New U.S. National Stage of PCT/JP2004/018702		
			APPLICANTS Yasufumi NISHII et al.			
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